Applicant(s): Tomohiko SHIBATA, Yukinori NAKAMURA, Mitsuhiro TANAKA and Keiichiro ASAI
Title: A METHOD FOR FAB
TING A III-V NITRIDE FILM AND AN AP
THE SAME

Our Docket No.: 782\_193

1/3

FIG. 1A

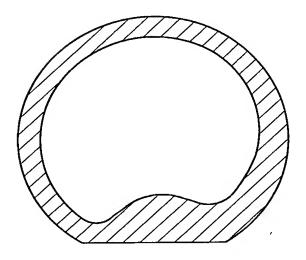
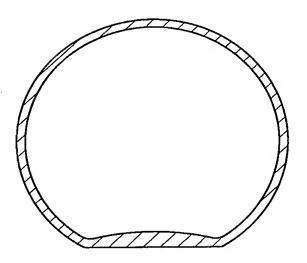


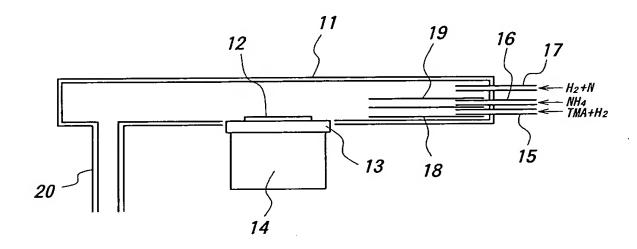
FIG. 1B



Our Docket No.: 782\_193

2/3

FIG. 2



Our Docket No.: 782\_193

3/3

FIG. 3

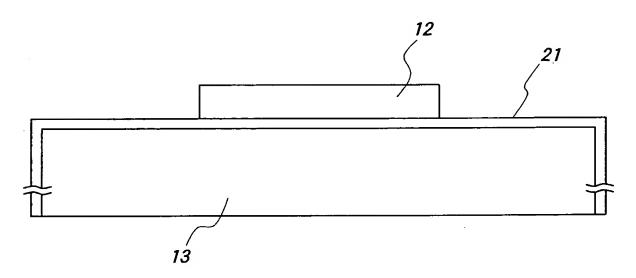


FIG. 4

